Si – SiO₂ – poly-Si interface

Cross-sectional transmission electron microscopy (XTEM) image of Si - SiO₂ - poly-Si interface, Bell Labs.
PECVD Deposited SiO$_2$

SEM image of PECVD SiO$_2$ on InP. PECVD deposition results in conformal coverage. Brian Thibeault, UCSB.
SEM image of ICP SiN on InP. PECVD deposition results in conformal coverage. Ilan Ben-Yaacov, UCSB.